

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

Scott G. Meikle

Application No.

09/649,427

Confirmation No.: 7170

Filed

August 28, 2000

For

METHOD AND APPARATUS FOR FORMING A

PLANARIZING PAD HAVING A FILM AND TEXTURE

ELEMENTS FOR PLANARIZATION OF MICROELECTRONIC

**SUBSTRATES** 

Examiner

Charlotte A. Brown

Art Unit

1765

Docket No.

108298511US

(Client Ref. No.: 00-0176)

Date

October 3, 2002

Assistant Commissioner for Patents Washington, DC 20231

## RESPONSE UNDER 37 C.F.R. § 1.111

Dear Commissioner:

This paper responds to the Office Action in this patent application mailed July 3, 2002. Please reconsider the application in light of the following remarks.

In The Claims:

Please cancel claims 24-54.

A method for forming a planarizing medium for planarizing a 1. microelectronic substrate, comprising:

separating a planarizing medium material into discrete elements;